

U.S. Department of Commerce, Patent and Trademark Office		Atty Docket No.	Serial No.
		PSI004-1C US UNKNOWN	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT		Applicant(s)	
(Use several sheets if necessary)		; Kwon, joonhyung;	
		Filing Date	Group
		HEREWITH	

## U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	Re. 35,514	5/20/97	Albrecht et al	250	216	
	AB	5,103,095	4/7/1/92	Elings et al	250	306	
	AC	5,157,251	10/20/92	Albrecht et al	250	216	
	AD	5,376,790	12/27/94	Linker et al	250	306	
	AE	5,714,756	2/3/98	Park et al	250	306	
	AF	5,854,487	12/29/98	Braunstein et al	250	306	
	AG	5,877,891	3/2/99	Park et al	359	372	
	AH	5,939,719	8/17/99	Park et al	250	306	
	AI	6,057,546	5/2/00	Braunstein et al	250	306	
	AJ	6,057,547	5/2/00	Park et al	250	307	
	AK	6,185,991 B1	2/13/01	Hong et al	73	105	
	AL	6,310,342 B1	10/30/01	Braunstein et al	250	306	

## Foreign Patent Documents

Translation

		Document	Date	Country	Class	Subclass	Yes	No

## OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

	AQ	Binnig G., et al, "Atomic Force Microscope", <i>Physical Review Letters</i> , Vol 56, No. 9, 3 March 1986 pages 930-933
	AR	Hansma, P.K., et al, "A new, optical-lever based atomic force microscope", <i>J. Appl. Phys.</i> , 76(2) 15 July 1994, American Institute of Physics, pages 796-799
	AS	Meyer, Gerhard et al, "Erratum: Novel optical approach to atomic force microscopy", <i>Appl. Phys. Lett.</i> 53(24), 12 December 1988, American Institute of Physics, pages 2400-2402
	AT	"Dimension 3100 Scanning Probe Microscope The Most Versatile SPM Ever Manufactured", <a href="http://www.di.com/Products/Dim/3100/D3100Main.html">www.di.com/Products/Dim/3100/D3100Main.html</a> , Digital Instruments, Veeco Metrology Group ©1998-2001, print date 12/17/2001, 4 pages

Examiner Date Considered

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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	AU						
	AV						
Foreign Patent Documents							
		Document	Date	Country	Class	Subclass	Translation
	AW						Yes
	AX						No
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
	AY	"Dimension 3100 Scan Techniques Unparalleled Power and Versatility", <a href="http://www.di.com/Products/Dim/3000/D31.scantechiques.html">www.di.com/Products/Dim/3000/D31.scantechiques.html</a> , Digital Instruments Veeco Metrology Group, ©1998-2001, print date 12/17/2001, 2 pages					
	AZ	Babcock, K.L. et al, "Phase Imaging: Beyond Topography", <i>Digital Instruments</i> , 3 pages (believed to be prior to 2-15-02)					
	BA	"AutoProbe CP-Research AP-2001", ThermoMicroscopes, 5 pages (believed to be prior to 2-15-02)					
	BB	"AutoProbe CP Research Scanning Probe Microscope", ThermoMicroscopes, 4 pages (believed to be prior to 2-15-02)					
	BC	"AutoProbe MSE AP-5001", ThermoMicroscopes, 4 pages (believed to be prior to 2-15-02)					
	BD	AutoProbe M5™ Scanning Probe Microscope, Microscopes Veeco Metrology Group, 2001© TM Microscopes, Veeco, 4 pages					
	BE	"TappingMode Imaging: Application and Technolofy", <a href="http://www.di.com/AppNotes/TapMode/TapModeMain.html">www.di.com/AppNotes/TapMode/TapModeMain.html</a> , Digital Instruments, Veeco Metrology Group, ©1995-2001, Digital Instruments, print date 12/17/2001, 5 pages					
	BF	"NanoScope Vertical Engage Scanner", <a href="http://www.di.com/Products/Mult/JVScanner.html">www.di.com/Products/Mult/JVScanner.html</a> , Digital Instruments Veeco Metrology Group, ©1996-2001, Digital Instruments, print date 12/17/2001, 1 page					
	BG	"NanoScope MultiMode Scanning Probe Microscope", <a href="http://www.di.com/products/Multi/MM Alone.html">www.di.com/products/Multi/MM Alone.html</a> , Digital Instruments Veeco Metrology Group, © 1996-2001, Digital Instruments, 8 page					
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	BH							
Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	BI							
	BJ							
	BK							
	BL							
	BM							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
	BN	“NanoScope ® MultiMode™ SPM The World’s Highest Resolution SPM”, <a href="http://www.di.com/Products/Multi/MMMain.html">www.di.com/Products/Multi/MMMain.html</a> , Digital Instruments Veeco Metrology Group, ©1995-2001, Digital Instruments, print date 12/17/2001 7 pages						
	BO	“Products”, Digital Instruments, Veeco Metrology Group Products, <a href="http://www.di.com/products2/products_all.html">www.di.com/products2/products_all.html</a> , print date 12/17/01, 5 pages						
	BP	“AutoProbe CP Research The Most Flexible Research SPM”, <a href="http://www.theermicro.com/products/cp.htm">www.theermicro.com/products/cp.htm</a> , Microscopes Veeco Metrology Group, ©2001, print date 12/17/01, 2 pages						
	BQ	Manalis, S. R., et al, “High-speed atomic force microscopy using an integrated actuator and optical lever detection”, Rev. Sci. Instrum. 67(9), September 1996, pages 3294-3297						
	BR	“The Dimension™ 5000 Scanning Probe Microscope”, Digital Instruments, 8 pages <i>(believed to be prior to 2-15-02)</i>						
	BS	“The Dimension™ 3000 Scanning Probe Microscope”, Digital Instruments. 6 pages <i>(believed to be prior to 2-15-02)</i>						
	BT	“The Enhanced Dimension™ 3100 Scanning Probe Microscope”, Digital Instruments, 1 page <i>(believed to be prior to 2-15-02)</i>						
	BU	“Microlevers™ General Purpose Cantilevers”, Park Scientific Instruments © 1998, 1 page <i>(believed to be prior to 2-15-02)</i>						
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U.S. Department of Commerce, Patent and Trademark Office			Application No.:	Unknown				
			Filing Date:	Unknown				
INFORMATION DISCLOSURE STATEMENT BY APPLICANT			First Named Inventor:	Joonhyung Kwon				
(Use several sheets if necessary)			Group Art Unit:	Unknown				
			Examiner Name:	Unknown				
			Confirmation No.:	Unknown				
			Attorney Docket No.:	PSI004-1C US				
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	1.	6,144,028 A	11-2000	Kley, Vic B.	250	234		
	2.	5,705,814 A	01/1998	Young et al.	250	306		
	3.	2002/0148955 A1	10/2002	Hill, Henry A.	250	234		
	4.	5,939,709 A	08/1999	Ghislain et al.	250	216		
	5.	5,672,816 A	09/1997	Park et al.	73	105		
	6.	5,210,410 A	05/1993	Barrett, Robert	250	234		
	7.	6,169,281 B1	01/2001	Chen et al.	250	234		
	8.	5,948,972 A	09/1999	Samsavar et al.	73	105		
Foreign Patent Documents							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
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